

**Amendments to the Specification:**

On pages 7-8 of the specification, please replace the paragraph beginning at p. 7 line 15 with the following amended paragraph:

In light of the foregoing realizations the present inventors determined that the traditional probe station should be modified in some manner to facilitate at least partial independent movement or otherwise separation of the optical probes and electrical probes. Referring to FIG. 7, a modified probe station 100 includes a chuck 102 that supports a device under test 104. The device under test 104 in many instances is one or more photonic devices. An upper platen 106 defines an opening 108 therein and is positioned above the chuck 102. The opening 108 may be, for example, completely encircled by the upper platen 106 or a cutout portion of the upper platen 106. Electrical probes 110 are supported by the upper platen 106. The platen 106 is supported by a plurality of supports 112A, 112B, 112C, and 112D. Positioned below the supports 112A-112D ~~112a-112d~~ is a lower platen 114. The optical probes 116 are supported by the lower platen 114. A microscope, not shown, may be used to position the device under test 104 relative to the probes 110 and 116. During probing the upper platen 106 is moved in a z-axis direction to make contact between the electrical probes 110 and the device under test 104. The x and/or y position of the chuck 102 (hence the device under test 104) relative to the electrical probes 110 is modified, and thereafter the upper platen 106 is moved in a z-direction to make contact between the electrical probes 110 and the device under test 104. During testing the optical probes 116 are aligned with the edge of the device under test 104.